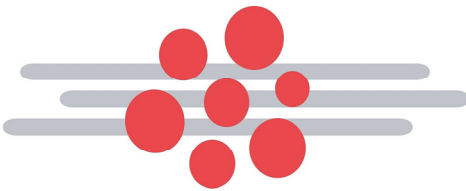


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	REVISION 0.1
Subject: Using the Technics PE-IIA Plasma Asher	DATE 12/17/2007
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- 1.0 Set up conditions:
 - 1.1 Turn on the pump via the switch along the wall labeled “Asher pump switch”
 - 1.2 Turn on Power switch
 - 1.3 In general it is advised to use the manual mode – make sure the switch is in the manual position.
 - 1.4 Close the lid. Switch the vent solenoid to “closed.”
 - 1.5 Now pump down the chamber using the vacuum solenoid to open.
 - 1.6 Read the chamber pressure. It should pump down relatively quickly to the 0.05 Torr range.
 - 1.7 After it has pumped out, flow the O₂ gas by turning Gas #1 on. Adjust the pressure by turning the gas flow.
 - 1.8 When the O₂ pressure is as desired, turn the RF power on. Make sure there is a plasma by looking through window. Set the power as you’d like.
- 2.0 When the conditions are satisfactory, turn off power, turn gas flow off and switch vacuum solenoid off.
- 3.0 Vent the chamber by switching the vent solenoid to the “open” position. When the chamber is vented, open the chamber lid carefully.
- 4.0 Load your sample on the platen. Close the lid and repeat steps 1.4-1.7.
- 5.0 When the pressure is good, turn on power and ash for the desired amount of time.
- 6.0 After ashing, turn off power, gas flow and vacuum as in step 2.0. Vent the chamber again. Remove your sample.
- 7.0 When you are done using the asher:
 - 7.1 pump the chamber down to vacuum again.
 - 7.2 Turn off vacuum solenoid.
 - 7.3 Turn off power.
 - 7.4 Turn off vacuum pump with button on wall.